



Micro CMMs

SME MicroManufacturing Workshop

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Define Micro CMM

- **Small work volumes**
 - Typically 100mm x 100mm x 100mm
- **Fine positional accuracy**
 - <300nm
- **Low contact force**
 - <1mN



Commercial Options

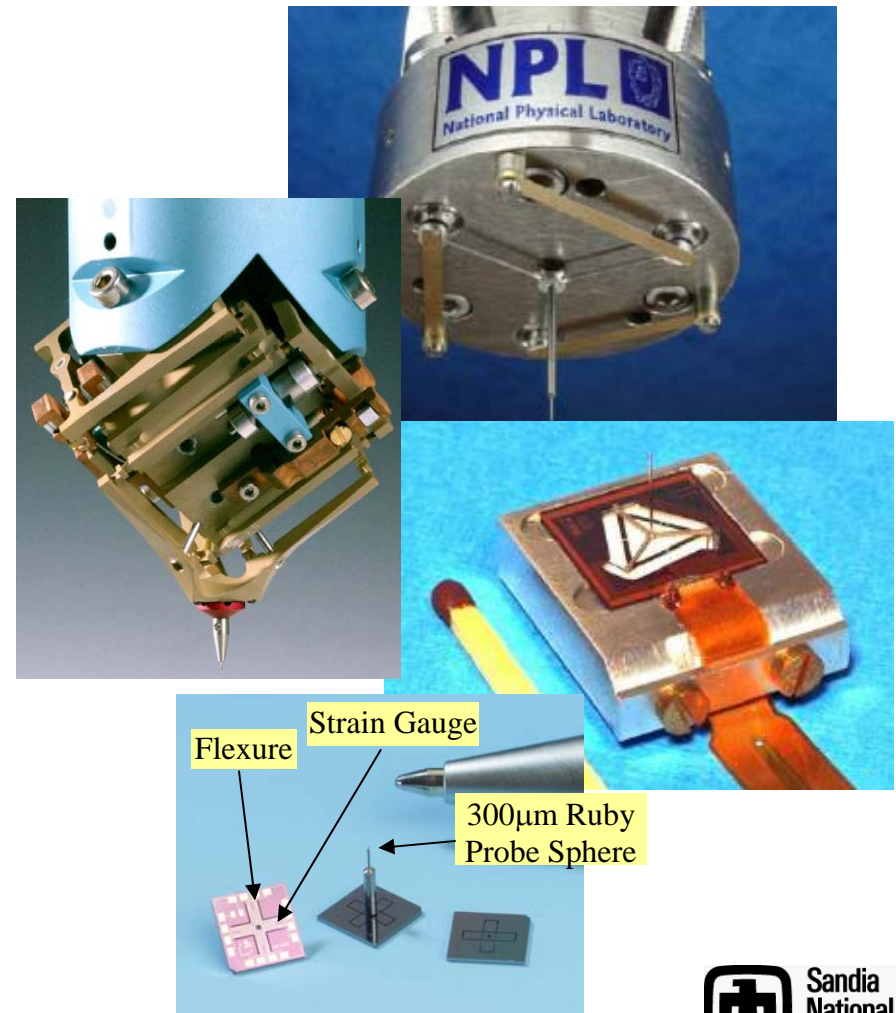
- **IBS**
 - ISARA
- **Mitutoyo**
 - UMAP
 - Nanocord
- **Zeiss**
 - F25
- **Non-commercial**
 - Many academic and NMI level projects





Contact Probing Technology

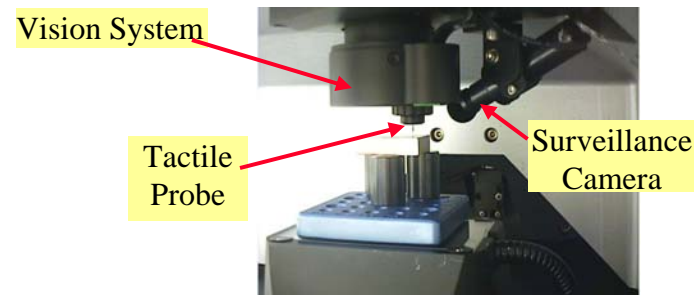
- MEMS Based
- Flexure / Capacitance
- Force gauges





Vision Probes

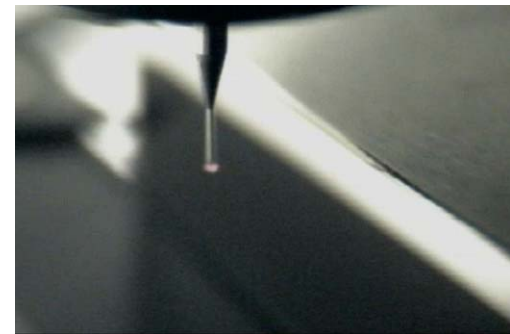
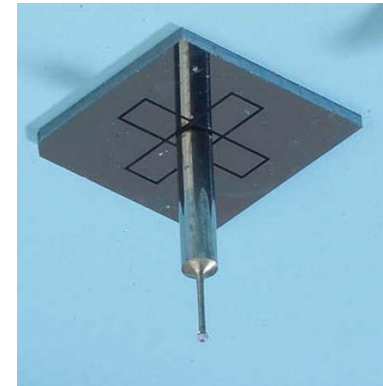
- Most systems have both tactile and vision probing options
- Increases calibration complexity
- Registration of coordinate frames





Probe Access

- Probe access is limited
- Gauging point (B89) on a gauge block inaccessible
- X-Z and Y-Z angles can be challenging





Calibration Concerns

- **Users should at least establish a verification procedure**
- **Optimally, users should be able to calibrate their own equipment**
- **Keep the tests simple (e.g., gauge blocks)**
 - **Wringing skill**



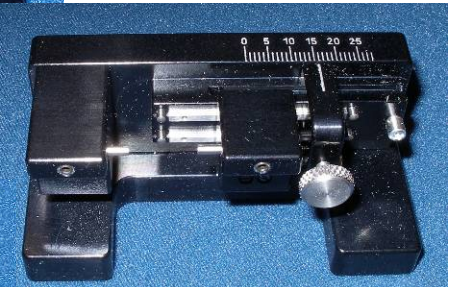
Operator Finesse

- **Checklists**
- **Change in attitude**
 - Much more technical
 - “Virtual” operation
- **Cleaning**
- **Heat transfer**
- **Everything matters**



Fixturing

- Low contact forces
- No fixturing required?
- Best practice is to fixture parts
- Fixturing Options
 - Clay – No!
 - Clamps
 - Magnets
 - Cyanoacrylate
 - Low and High Viscosity
 - Hot glue
 - Thermals





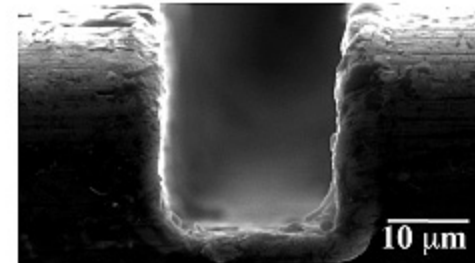
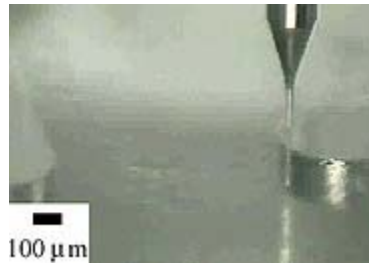
Important considerations for micro-CMMs

- **High purity cleaners**
 - Spectroscopic grade IPA
 - Spectroscopic grade Acetone
 - Caution
- **No canned/compressed air**
 - High force
 - Cools parts
- **Mechanical cleaning of probes may be done with extreme care**
- **Characterization of probe**
 - Full: Once per installation
 - Fine tune: Daily

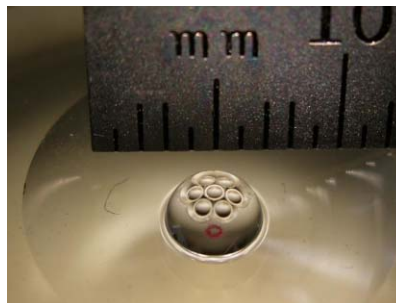
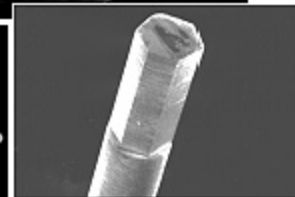


Sandia's Experience

- Sandia designs and manufactures a range of meso-scale components



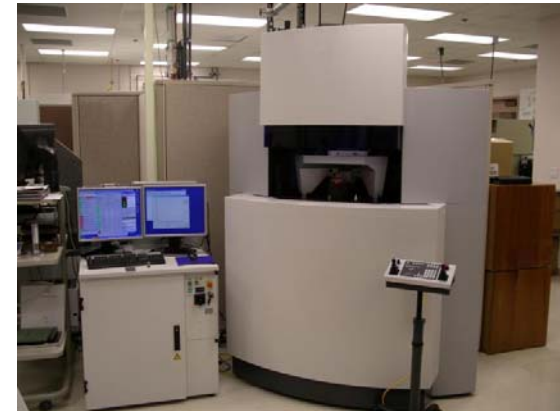
A 25-µm end mill tool (right), with five cutting edges, was fabricated using focused ion beam machining. The end mill was used to make this 25-µm deep channel (above) in aluminum.





SNL has acquired a micro-CMM.

- Meso-scale manufacturing and system development area
 - 10^1 mm in size
 - 10^{-1} mm features
 - 10^{-3} mm tolerances
- MPE_E of $(0.250+L/666)\mu\text{m}$
- 0.5mN probing force
- 100mm x 100mm x 100mm work volume
- Tactile and vision probes
- Surveillance camera for operation





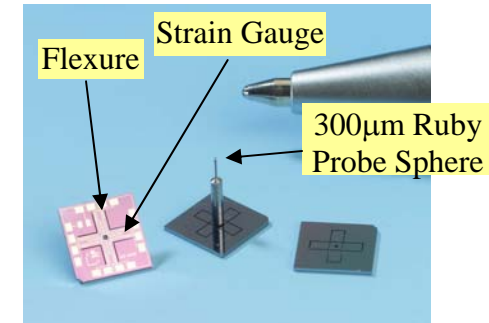
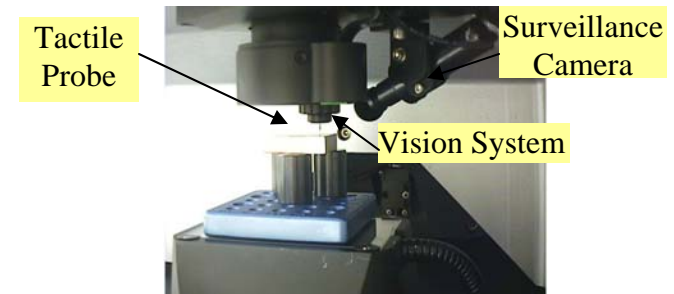
Precision design principles support accuracy claims by vendor

- **Dual bridge design minimizes Abbe offsets**
- **Air bearing design modifications increases stiffness**
 - **>40 air bearings**
- **Vibration isolation**
- **Thermal shielding**
- **Glass scales**
- **Linear motors**
 - **Heat generation proportional to load**



Silicon flexure tactile probe applies low contact force, $\sim 0.5\text{mN}$

- $120\mu\text{m}$ and $300\mu\text{m}$ diameter probes readily available
- Flexure + strain gauge sensing technology
 - Analog nature enables scanning
- Force-deflection response linearized during special calibration
- Max deflection is $\sim 100\mu\text{m}$





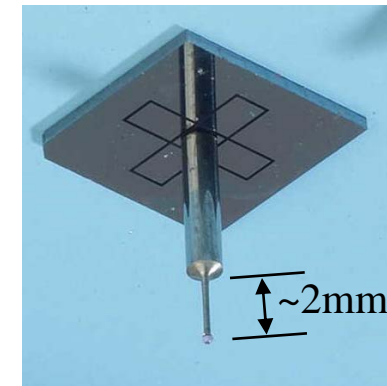
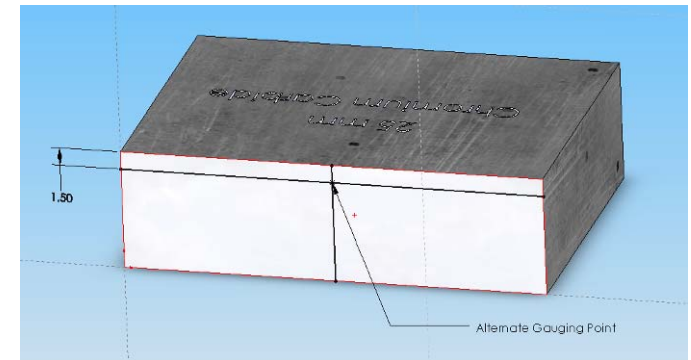
Force-Deflection Linearization Video

Probe Boss
Factor
Calibration



Evaluation requires special calibration of gauge blocks

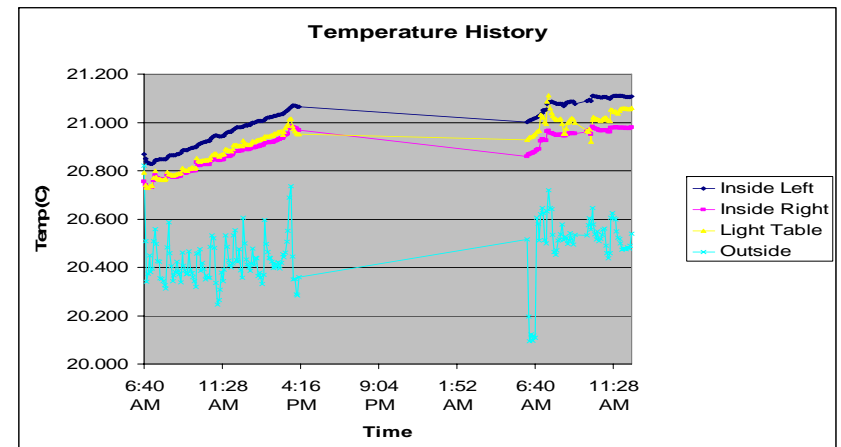
- Shank length is approximately 2mm
 - 300 μ m sphere / 200 μ m shaft
 - 120 μ m sphere / 50 μ m shaft
- Unable to reach standard gauging point
- Alternate gauging point as shown (1.5mm down)
- Certification by SNL primary standards laboratory on gauge block interferometer





Temperature and cleanliness are important at these levels

- **Temperature**
 - Absolute and gradient restrictions
 - Manual thermal compensation for this study
 - Minimize handling
- **Cleaning**
 - Spectroscopic grade IPA and acetone
 - Probe is delicate

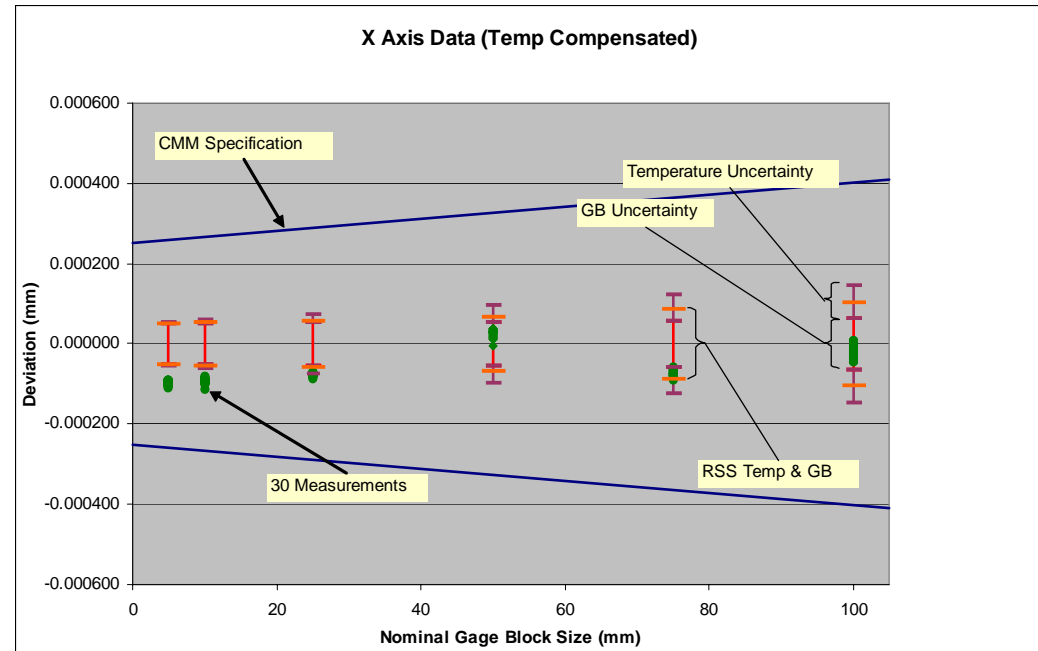


Probe
Cleaning



X-Axis Results

- Excellent repeatability
- Well within specification



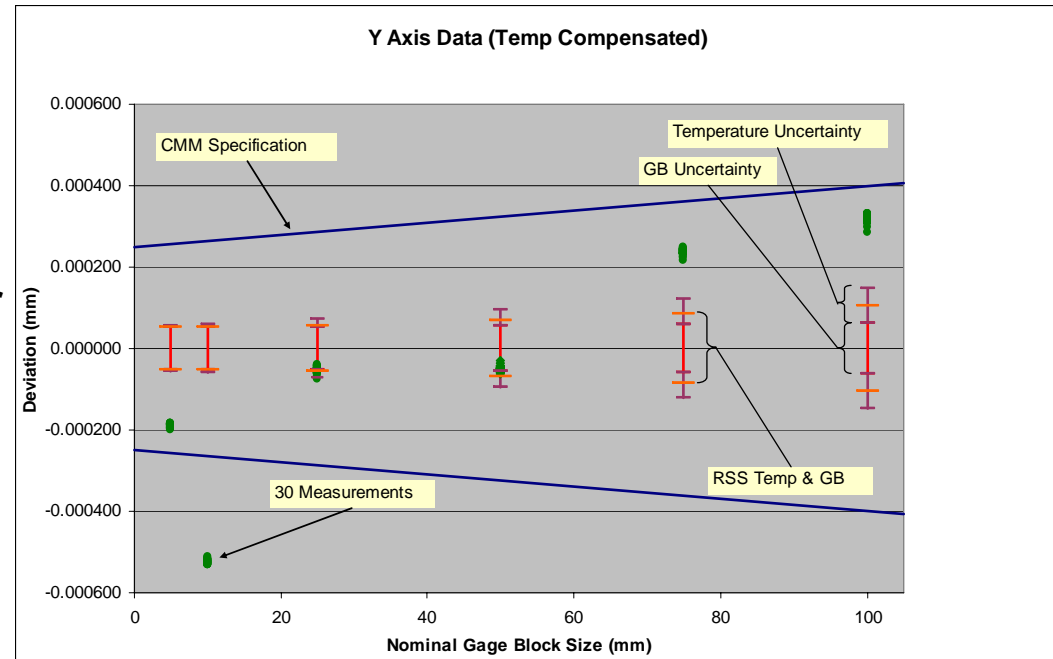
Temperature compensated x-axis results.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	21 nm	32	16	45	32	54
Average	-98 nm	-93	-77	25	-74	-17
Std. Dev.	5 nm	6	4	10	7	16
F25 Spec +/-	258 nm	265	288	325	363	400



Y-Axis Results

- Excellent repeatability
- One set of outliers
 - Dust?
 - Not supported by other measurements
- Balance within specification



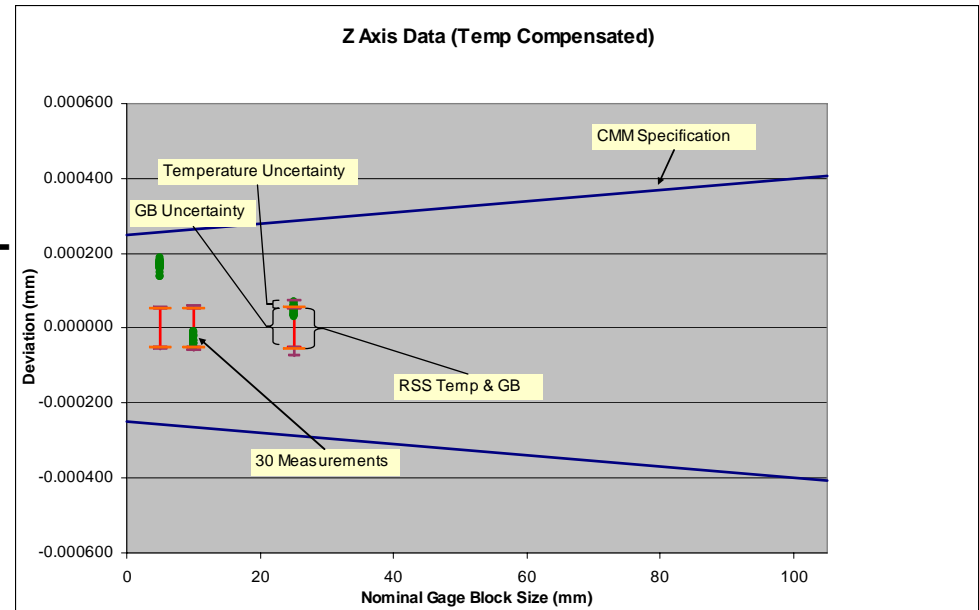
Temperature Compensated Y-Axis Results.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	17 nm	22	37	33	35	49
Average	191 nm	-524	-54	-49	237	320
Std. Dev.	5 nm	5	8	7	7	11
F25 Spec +/-	258 nm	265	288	325	363	400



Z-Axis Results

- Mechanical constraints reduce gauge block set
- Sample repeatability as x- and y-axes
- Within specification



Temperature compensated z-axis data.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	50 nm	45	41	NA	NA	NA
Average	168 nm	-31	49	NA	NA	NA
Std. Dev.	11 nm	12	12	NA	NA	NA
F25 Spec +/-	258 nm	265	288	325	363	400



Squareness Results

- 75mm gauge block in x-y plane
- 0.675 arcsec out-of square

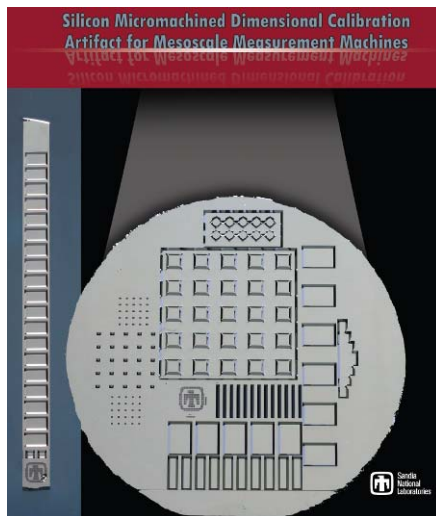
Squareness data.

	75mm (+X,+Y)	75mm (-X,+Y)
Range	21 nm	63
Average	-205 nm	286
Std. Dev.	5 nm	14



Advanced Calibration and Tactile/Vision Registration

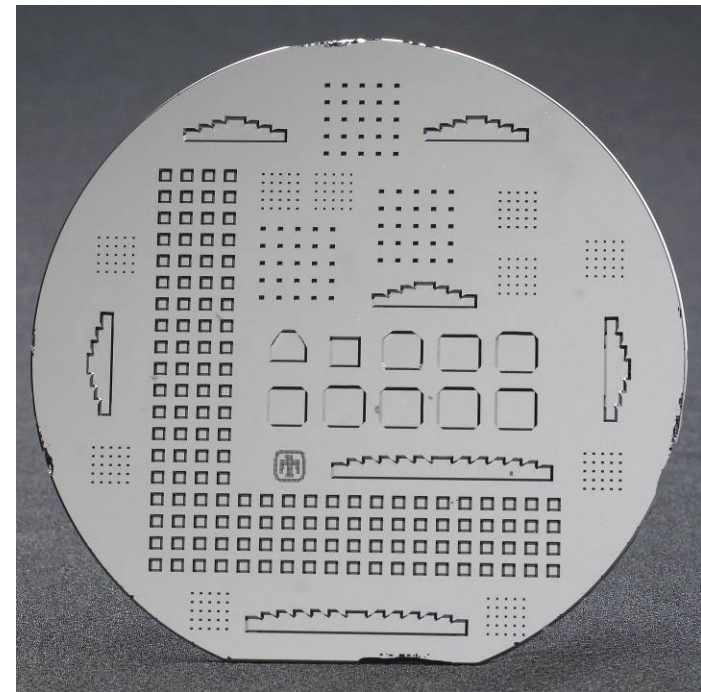
- R&D effort to improve calibration
- Silicon bulk micromachining
- Take advantage of crystal structure intrinsic properties
- 2008 R&D 100 Award Winner





Design Details

- **Bulk-etched Si**
 - $\langle 100 \rangle$, gives sidewalls 54.74 degrees from horizontal
 - 1.5 mm thick wafer, polished on both sides
 - KOH etchant
- **Geometric Features**
 - “step gages”
 - “ball plates”
 - Additional shapes





Final Points

- **Jump from traditional to micro CMMs larger than expected**
- **Probes are expensive**
- **Opportunity to train a new operator**
- **Clean, clean, clean**
- **Checklists**
- **Video capture for surveillance camera**
 - **Additional surveillance cameras**



Discussion
